

## **ABSTRACT**

A substrate processing system includes a measurement device, a transfer device, a map creating device, and an evaluation device. The measurement device measures errors of substrates after the substrates are subjected to processing of a first process by a first processing apparatus that performs the processing of the first process on the substrates. The transfer device transfers the substrates between apparatuses including the first processing apparatus, a second processing apparatus that performs processing of a second process on the substrates after the first process, and the measurement device. The map creating device creates, for each of the substrates, an error map indicating a distribution of the errors on the substrates. The evaluation device calculates, for each of the substrates, an evaluation value indicating a degree of importance of the errors based on the error map. The evaluation device instructs the transfer device on a transfer destination of the substrates subjected to the first process according to a determination result as to whether or not the evaluation value is equal to or larger than a predetermined first threshold value.

(Fig. 1)